

Dual-Channel Microfluidic Photoionization Detector

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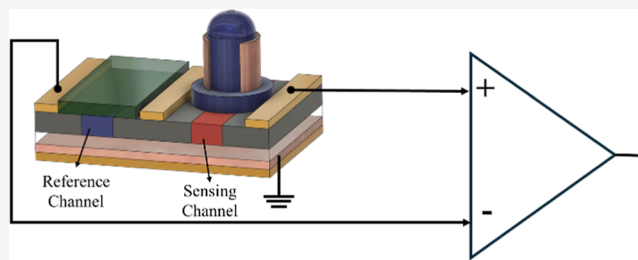


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ABSTRACT: Microfluidic photoionization detectors (μ PIDs) have long served as a highly sensitive gas sensor in a microgas chromatography (μ GC) device. However, their high electrical impedance renders them susceptible to various noise sources, often hindering their performance and bandwidth. Here, we developed a silicon-based, microfluidic differential dual-channel photoionization detector (μ DPID) to reject common-mode noises and enhance operational reliability under varying environmental conditions. Comprehensive analyses of the μ DPID were conducted by benchmarking its performance against the corresponding μ PID configuration for different noise sources. Experimental results demonstrate that the μ DPID significantly enhances noise immunity, providing a linear dynamic range of $\sim 2 \times 10^5$ (from 38.5 nA to 0.21 pA) at a large bandwidth of 106 Hz. These advancements underscore the μ DPID's potential for developing high-performance μ GC systems such as portable ultrafast GC and comprehensive 2-dimensional GC for rapid, in situ trace vapor detection.



INTRODUCTION

Rapid in situ vapor analysis has become increasingly important across various sectors, including healthcare,^{1–8} environmental surveillance,^{9–11} space exploration,¹² and food safety.^{13–15} Microgas chromatography (μ GC)^{1,2,9,14,16,17} is extensively used for these applications due to its ability to identify a broad range of gases and compact size. Various miniaturized gas detectors (summarized in Table S1) have been developed for use with μ GC. Among these, the microfluidic photoionization detector (μ PID)^{16–20} is especially popular because of its fast response, high sensitivity, simple manufacturing, and low power requirements.^{16,18,20,21}

We previously developed a silicon chip-based microfluidic μ PID,^{16,18} which has a small ionization chamber volume (5–7 μ L) and a flow-through structure (i.e., nearly zero dead volume). When used in GC, a detection limit of a single-digit ppt (in 1 L of sample) has been achieved.^{16,18} However, compared to other microgas detectors listed in Table S1, this μ PID is a high-impedance (on the order of G Ω to T Ω) current source, making it particularly vulnerable to various noise sources summarized in Table S2. Unfortunately, some of these noises, such as ambient-coupled noise and electromagnetic interference (EMI) noise²² cannot be mitigated solely by using expensive and bulky benchtop electrometers, which are often impractical for use in portable field applications.

Although using low-pass filters helps dampen some of these noises, as used in our previous designs^{16,18} (0.68 mV noise with a benchtop amplifier at a 10 Hz cutoff frequency and 0.016 mV noise with an in-house developed circuit at a 1.5 Hz cutoff frequency), the variability of the noise sources often reduces the efficiency of these filters. Additionally, adding a

filter significantly reduces the speed of the μ PID, which limits the μ PID's use in ultrafast GC^{23,24} and comprehensive 2-dimensional GC^{25,26} that has a subsecond peak width in second-dimensional separation. To increase bandwidth while minimizing noise, here we introduce a microfluidic differential dual-channel μ PID (μ DPID) with an on-chip heater shown in Figure 1A. It features two microfabricated channels on the same silicon chip: one functions as a standard μ PID (the “sensing channel”), and the other as a reference (the “reference channel”). This differential design greatly suppresses common-mode noises, leading to a bandwidth of 106 Hz and a linear dynamic range of $\sim 2 \times 10^5$ (from 3.85 V to 0.021 mV or 38.5 nA to 0.21 pA) without additional signal processing.

MATERIALS AND METHODS

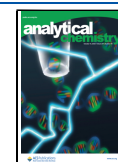
Materials. P-type/boron prime silicon (Si) wafers (100 mm in diameter, 400 μ m thick, 0.001–0.005 Ω cm, double-sided-polished (DSP)) were from Ultrasil. Borofloat 33 Pyrex glass wafers (P/N: 517) were from University Wafer. Kr VUV lamp (P/N: 043-257) and piD-TECH eVx Red Label (0–200 ppm) Plug-In PID Sensor (P/N: 045-012) were from MOCON (part of AMETEK). INA121 Instrumentation Amplifier (P/N: INA121P) was from Texas Instruments. ADS1262 32-bit precision Sigma Delta ADC breakout board

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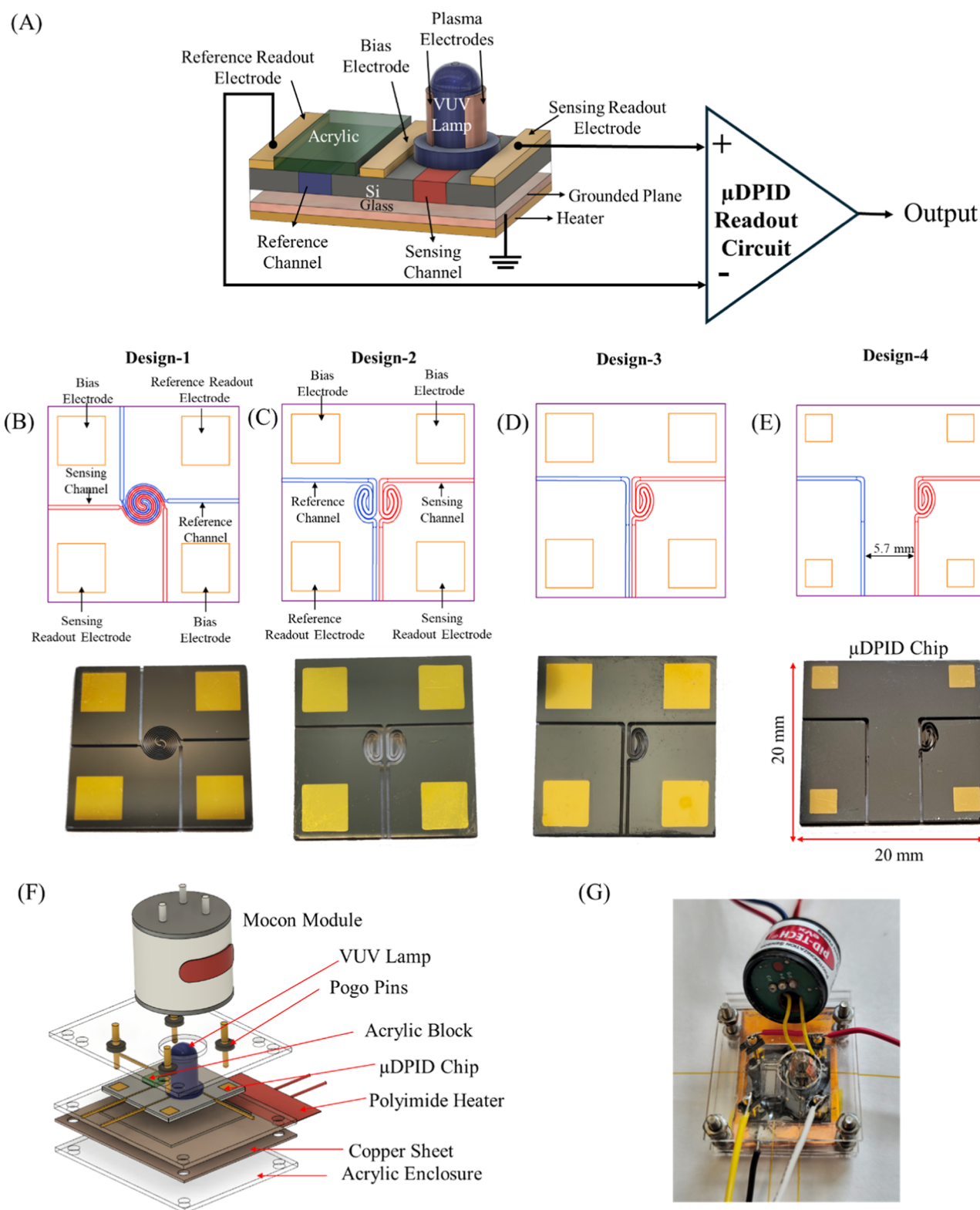


Figure 1. (A) μ DPID device consisting of a μ DPID module, an associated readout circuit, and an auxiliary power supply circuit (not shown). (B–E) Four μ DPID designs explored in this work: (B) Co-spiral channels. (C) Side-by-side spiral channels. (D) Straight-spiral channels side-by-side. (E) Straight-spiral channels with a spacing of ~ 5.7 mm. Design-1 and Design-2 are geometrically symmetrical. Design-3 and Design-4 are geometrically asymmetrical, since the reference and sensing channels have different shapes. The blue channel and red channel in the top panel denote the reference and sensing channels, respectively. The corresponding specifications of these four designs are listed in Table S3. (F) Exploded view of a μ DPID module using a Design-4 chip. (G) Corresponding photo. Note that the Mocon module is intentionally tilted to show the VUV lamp underneath.

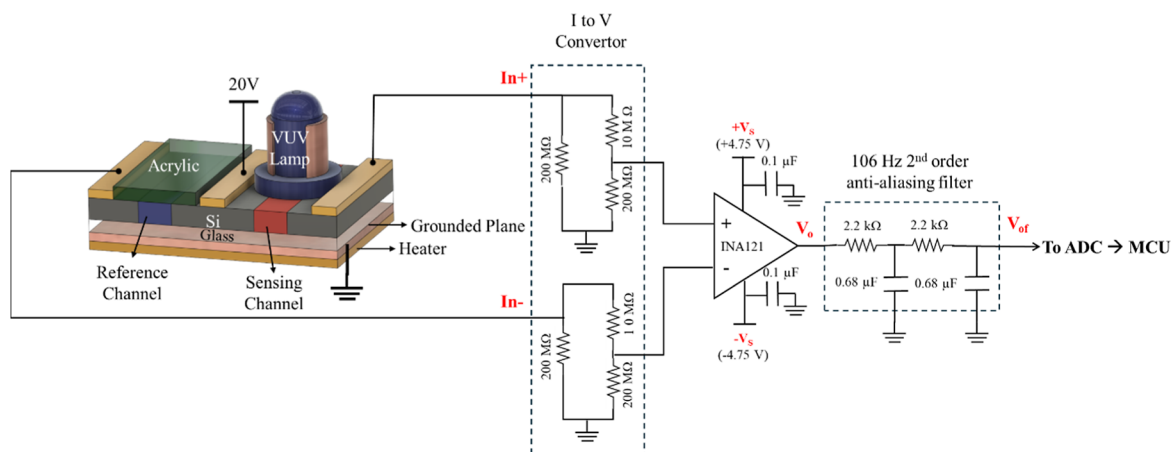


Figure 2. μ DPID readout circuit.

(P/N: PC-4143) was from Protocentral Electronics. Seeeduino XIAO NRF52840 SENSE—Microcontroller Unit (MCU) (P/N: 102010469) was from Seeed Technology Co., Ltd. Solid State Relay (SSR), CS326 was from Coto Technology. Polyimide Flexible Heater (P/N: PLMLV-101/10) was from Dwyer Instruments, LLC. 1/16" thick (P/N: 8560K178), 1/8" thick (P/N: 8560K199) Clear Scratch- and UV-Resistant Cast Acrylic Sheet, and 0.025" thick Super-Conductive 101 Copper Sheet (P/N: 89675K713) were from McMaster-Carr. 0.004" thick Conductive Copper Foil Adhesive Tape (P/N: 1067-1126-2-6-ND) was from DigiKey. UV-curable epoxy (P/N NOA 68T) was from Norland Products. Pogo pins were from Adafruit (P/N: 5381). Adafruit USB Isolator was (P/N: 2107) from Adafruit. Benzene (P/N: 270709-1L), Chlorobenzene (P/N: 23570-250 ML), and o-Xylene (P/N: 95662-250 ML) were from Sigma-Aldrich.

μ DPID Chip Fabrication. The fabrication process of the μ DPID chips is shown in Figure S1, which is adapted from the fabrication of our previous μ PID chip in 16,18. First, silicon and glass wafers were cleaned with a nanostrip solution, and then they were anodically bonded at 350 °C under vacuum. After bonding, the bonded wafer was cleaned again with the nanostrip solution to remove contaminants from the bonding chuck. A layer of photoresist (PR) was then patterned on the silicon side for deep reactive ion etching (DRIE) on silicon. Si was etched down completely (400 μ m deep) using DRIE to create microfluidic channels for the photoionization detector. The PR remaining on the silicon surface was then subjected to O₂ plasma cleaning to strip any remaining organics and remove any hardened PR residues on the silicon surface caused by the DRIE process. This was followed by deposition of Cr/Au on the silicon through an evaporation process using a silicon shadow mask to form the electrodes of the photoionization detector. Ion milling was also performed before metal evaporation on the silicon surface to remove any native oxide, enhancing the ohmic contact of the electrodes. Finally, the wafer was diced into \sim 20 mm \times 20 mm pieces (see Figure 1B–E, bottom panel). Four designs of the μ DPID chips were made, and their corresponding channel cross sections and lengths are given in Table S3.

μ DPID Packaging. For a fully packaged μ DPID module depicted in Figure 1F,G, the top surface of the sensing and reference channels of the Design-4 μ DPID chip (Figure 1E) was sealed with a VUV lamp and a laser-cut acrylic block, respectively, using UV-curable epoxy. Guard columns were

inserted into the fluidic ports of both the sensing and reference channels for the fluidic connection. A MOCON piD-TECH module was used to excite the plasma in the VUV lamp through conductive copper tape affixed to the VUV lamp electrodes.

All the electrical connections to the μ DPID chip were achieved via spring-loaded pogo pins affixed to a laser-cut acrylic enclosure. Figure 1F,G show the exploded view and a photo of the final packaged μ DPID module, respectively. Note that the carrier gas (such as helium or nitrogen) and analytes flow through the sensing channel during actual operation. The reference channel can be filled with either carrier gas or ambient air. However, flowing carrier gas through the reference channel is more complicated (since it requires an additional connection to the carrier gas) and consumes additional gas. Therefore, in this paper, we simply let the reference channel be filled with ambient air.

Experimental Setup for μ DPID as GC Detector. To evaluate the performance of the μ DPID at 23 °C (room temperature) and 50 °C, we chose Benzene (C₆H₆, boiling point: 80.1 °C, ionization potential: 9.25 eV), Chlorobenzene (C₆H₅Cl, boiling point: 132 °C, ionization potential: 9.07 eV), and o-Xylene (C₈H₁₀, boiling point: 144 °C, ionization potential: 8.56 eV) as model systems. Gas samples for these analytes were collected from the headspace of screw-thread vials using a gastight syringe, then injected into the injector of the HP 6890 series GC System, which operated at 300 °C with a split ratio of 30, using helium as the carrier gas. The injection port outlet was connected to the μ DPID's sensing channel via a 34-in. guard column, while its reference channel was left open to the ambient. The other end of the μ DPID's sensing channel was connected to the Flame Ionization Detector (FID) in the HP 6890 through a 29-in. guard column. Both the 34-in. and 29-in. guard columns were maintained at room temperature. The flow rate at the inlet of the FID was set to \sim 1 mL/min. The FID was set to operate at 250 °C, with a hydrogen flow rate of 40 mL/min and a dry air flow of 200 mL/min. Note, here we used the FID as a reference detector to characterize the μ DPID at 23 and 50 °C. The data sampling rate of FID was set to 100 Hz, and the μ DPID module signal bandwidth was set to 106 Hz. To monitor the thermal cycling performance of the μ DPID module with the VOCs detection, data were initially obtained at 23 °C for #1–23 °C. The module was then heated for approximately 15 min to reach

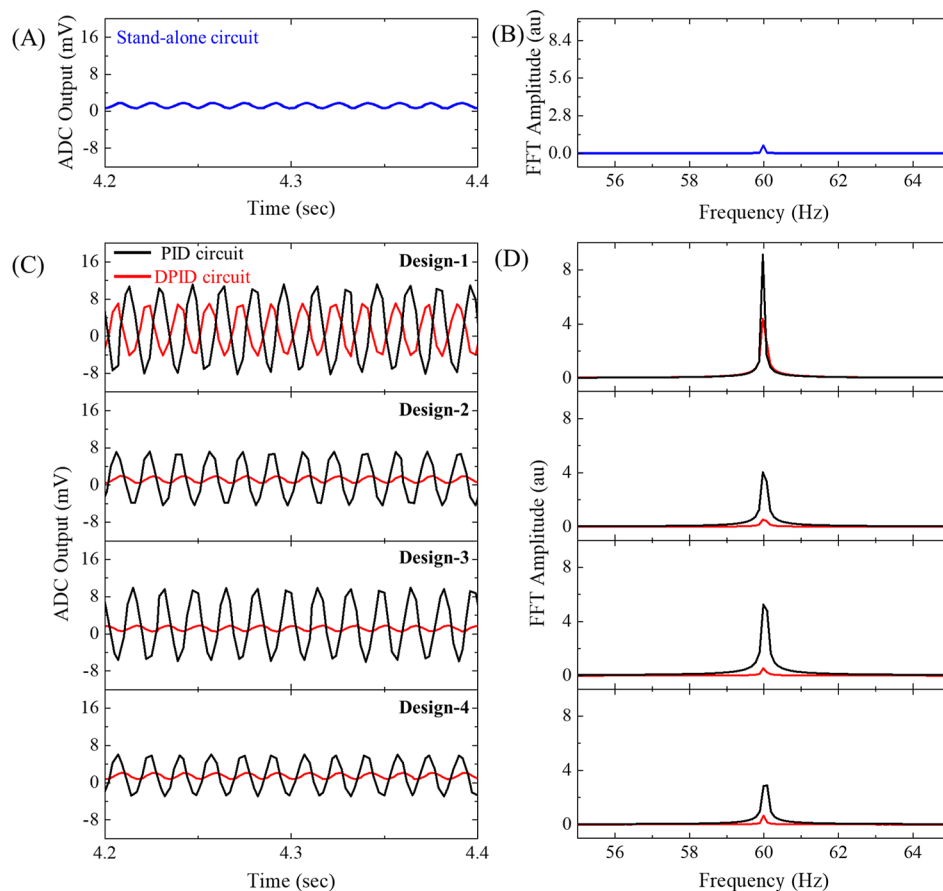


Figure 3. Ambient-coupled noise analysis of μ DPID chip designs with the circuit configuration shown in Figure S5 without a Faraday cage. (A) ADC output snippet for the standalone readout circuit. (B) Corresponding FFT spectrum. (C) ADC output snippets for both the μ DPID circuit (red) and the μ PID circuit (black). (D) Corresponding FFT spectra. All the noise values are tabulated in Table S6. All the signals were recorded with a bandwidth of 106 Hz for 10 s at 23 °C. All the characterizations were performed with the μ DPID chip sandwiched between laser-cut acrylic sheets with the electrodes exposed.

around 50 °C to collect #2–50 °C data. Afterward, it was cooled back to 23 °C before recording the #3–23 °C.

RESULTS AND DISCUSSION

The main components of a μ DPID device (depicted in Figure 1A) are a μ DPID module, consisting of a microfluidic chip and a vacuum ultraviolet (VUV) lamp, and a readout circuit, as well as an auxiliary power supply circuit, as described as follows.

μ DPID Module Design. A conventional μ PID^{16,18,20} chip consists of a single microfluidic channel (e.g., Archimedean spiral design in our previous work^{16,18}) with the two facing walls forming electrodes to collect electrons and ions under a bias voltage.¹⁸ In contrast, the μ DPID chip has two channels: a sensing channel and a reference channel. Gas detection occurs in the sensing channel with a VUV lamp on top. We examined four different μ DPID chip designs in Figure 1B–E. The μ DPID Chip Fabrication section discusses the methodology used for fabricating these chips.

To operate the μ DPID module at a higher temperature (50 °C in the current work), a polyimide heater (refer to Figure 1A,F) was mounted on the back of the μ DPID chip, with an intermediate grounded copper sheet insulated with Kapton tape (referred to as a “grounded plane”—see Figure 1A). As explained later, this setup shields the μ DPID chip from EMI caused by heater pulse width modulation (PWM). Although the current design utilizes an off-the-shelf heater, both the

grounded plane and heater can also be integrated into the μ DPID chip during the microfabrication process, thereby eliminating the need for manual assembly. Figure 1F,G show the components in the μ DPID module and the corresponding photo, respectively. The μ DPID Packaging section describes the details of the assembly processes.

μ DPID Readout Circuit Design. Figure 2 illustrates the readout circuit design for the μ DPID. A μ DPID chip comprises three electrodes (shown in Figure 1A): sensing readout, reference readout, and bias electrodes. Both the sensing and reference channels utilized the same bias electrode, to which a 20 V was applied. The sensing and reference readout electrodes were connected to the “In+” and “In−” terminals of the readout circuit, respectively. The currents produced by the sensing and reference channels were converted into voltage through a simple symmetric resistive network (equivalent resistance of $\sim 100 \text{ M}\Omega \pm 1\%$) constructed at the INA121 inputs for efficient common-mode rejection. This I to V conversion method is preferred over a transimpedance amplifier to prevent extra noise from entering the circuit. For maximal dynamic range, the INA121 was powered by a $\pm 4.75 \text{ V}$ bipolar voltage supply (see Section S5 for details on the choice of the amplifier voltage supply and the linearity test).

The output signal (V_{out}) from INA121 was subsequently fed to a 32-bit Analog-to-Digital Converter (ADC). To prevent

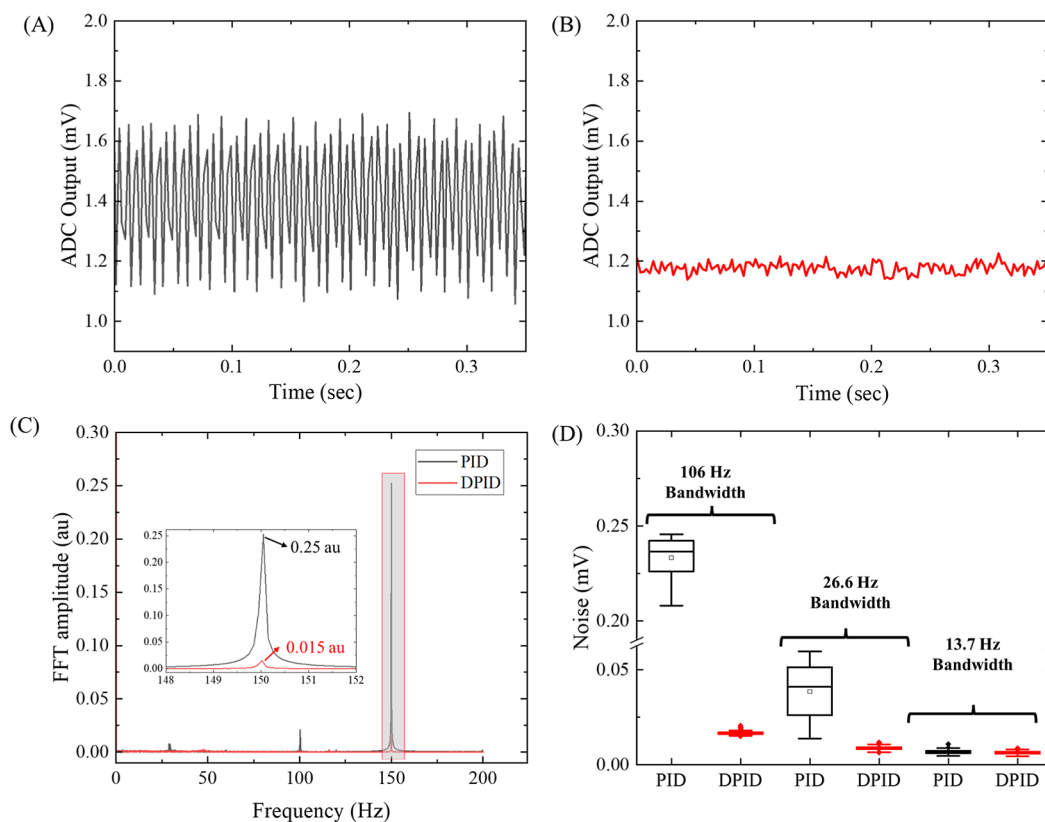


Figure 4. Heater-induced noise in a μ DPID chip. (A,B) 0.35 s snippets of μ PID (black) and μ DPID (red) signals, respectively, from Figure S12A recorded for 600 s with a 106 Hz bandwidth using the Design-4 μ DPID chip with the on-chip heater turned ON. (C) Corresponding FFT spectra of the μ PID and the μ DPID signals. The 150 Hz heater-related EMI FFT amplitude detected by the μ PID and the μ DPID is 0.25 and 0.015, respectively. (D) Noise distribution in the μ PID (black) and μ DPID (red) signal operated at 106, 26.6, and 13.7 Hz bandwidth with the heater ON for 600 s. The corresponding noise analysis is shown in Figure S12(D). The μ PID and μ DPID data were collected with an on-chip heater in the μ DPID chip operated by a unipolar 16 V, 150 Hz, and 80% duty cycle PWM signal. The heater was activated just immediately before the start of data collection. The initial temperature at $t = 0$ s was approximately 23 °C (room temperature) for all the bandwidths. All the characterizations were performed with the μ DPID chip sandwiched between laser-cut acrylic sheets with the electrodes exposed.

aliasing of unwanted high-frequency signals sent to the ADC, a second-order low-pass antialiasing RC filter with a cutoff frequency of 106 Hz was implemented to assist the built-in digital Sinc filter in the ADC. This RC filter uses a small resistor (~ 2.2 k Ω) to minimize signal offsets and decrease additional noise resulting from any leakage currents from the ADC input. In this work, the bandwidths used were 106, 26.6, and 13.7 Hz (see Section S6 for details on the ADC settings).

Finally, a microcontroller unit (MCU) was employed to collect the digitized ADC signal via SPI communication. The ADC data collected by the MCU was then streamed in real time to the LabVIEW program on the laptop via wired USB communication. A USB isolator was used to avoid unwanted noise, including 60 Hz power line interference injected into the μ DPID device through this USB communication. Section S7 describes the overall architecture for the μ DPID device.

Batteries, instead of a wall-mounted AC supply, were preferred for use with the μ DPID to avoid 60 Hz power line noise. Moreover, using batteries for portable applications is also simpler and more practical. Given the μ DPID's low power consumption (180 mW, due mainly to plasma excitation), a 16 V, 5000 mAh battery could last up to ~ 19 days of continuous operation without the heater being activated. With the μ DPID heater activated (<3 W for 50 °C), the batteries can last ~ 30 h.

Finally, the entire readout circuit, along with the μ DPID module, was enclosed in a solid Faraday cage made up of a

laser-cut acrylic box covered with adhesive conductive copper foil tape for reduced weight and improved thermal insulation (see Figure S3A).

Note that the μ DPID can be converted to a regular μ PID, i.e., our previous version reported in 16,18 by disconnecting the reference electrode from the "In-" of the readout circuit. This allows us to test the regular μ PID under otherwise identical conditions for comparison.

Readout Circuit Noise and Baseline Offset. As mentioned previously in Table S2, the μ DPID readout circuit (Figure 2), designed to amplify the μ DPID signal, also contributes considerable noise resulting from both voltage and current noise from the amplifier and thermal noise from various circuit components, including resistors and the amplifier. Section S8 provides a detailed noise analysis of the μ DPID's readout circuit. Table S5 summarizes the noise comparison of the readout circuit with the instrumentation amplifiers employed in both the previous^{16,19} and the current work, showing that INA121 used in the current work produces much lower noise than INA122 used previously,^{16,19} which results from the lower current noise of ~ 1 fA/Hz^{1/2} produced by INA121 than ~ 80 fA/Hz^{1/2} by INA122. Furthermore, Table S5 indicates that the predominant noise source in the current INA121-based readout circuit is the thermal noise (1.26 μ V/Hz^{1/2}) generated by the 100 M Ω resistor used for amplifying the current (in the pA range) from the μ DPID.

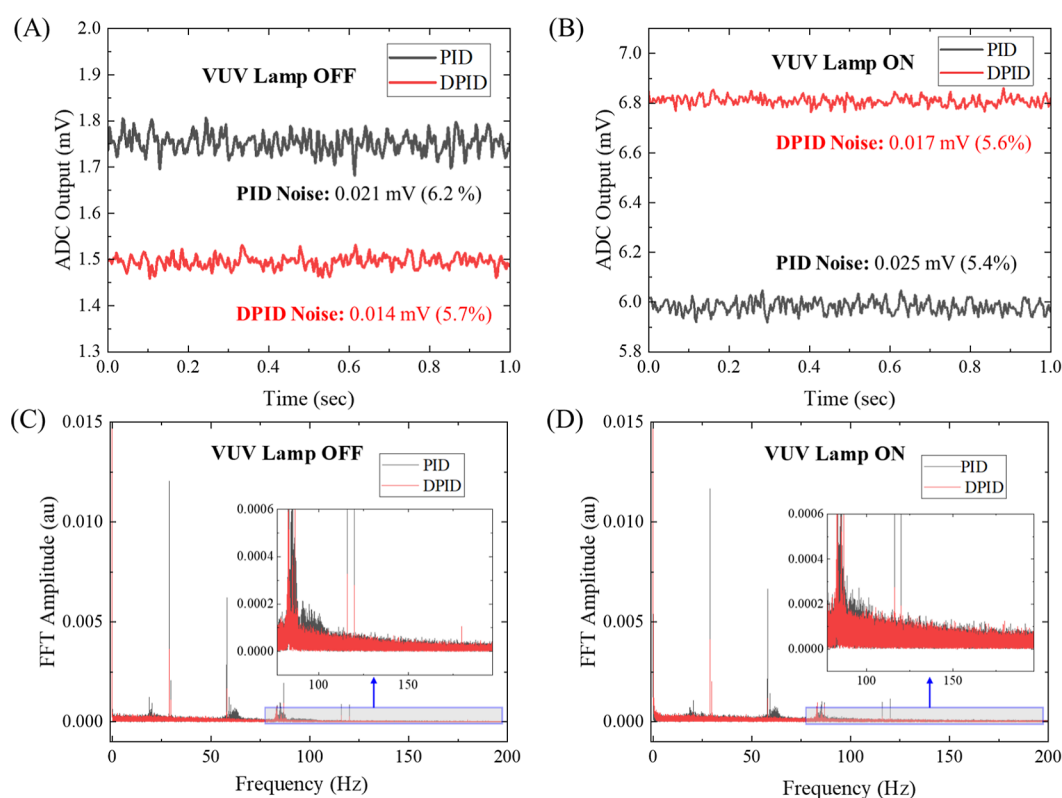


Figure 5. Contribution of plasma excitation-induced noise. (A,B) 1 s snippet of μ PID (black) and μ DPID (red) signals recorded with the VUV lamp OFF and VUV lamp ON, respectively, from Figure S15 for 300 s. Notably, the baseline of both signals in (B) increases by 4.3 mV for μ PID and 5.3 mV for μ DPID when the VUV lamp is ON. (C,D) Corresponding FFT spectra. The insets in (C,D) provide zoomed-in views of the shaded areas. All μ DPID and μ PID signals were recorded with a bandwidth of 106 Hz at 23 °C. Helium gas was flowed at a rate of 3 mL/min in the sensing channel of the μ DPID, whereas the reference channel was left open to the ambience.

Table 1. Comparison of the Noise Levels of μ DPID and μ PID Recorded Over a Duration of 300 s at Different Bandwidths (106, 26.6, and 13.7 Hz), for Conditions: VUV Lamp OFF and Heater OFF, VUV Lamp ON but Heater OFF, and Both VUV Lamp and Heater ON^a

setup	bandwidth (Hz)	noise with heater OFF (mV)		noise with heater ON (mV)
		VUV lamp OFF	VUV lamp ON	VUV lamp ON
μ PID	106	0.021 (6.2%)	0.025 (5.4%)	0.2 (2.0%)
	26.6	0.012 (8.2%)	0.013 (8.4%)	0.03 (34.4%)
	13.7	0.0076 (8.4%)	0.0076 (9.8%)	0.0065 (11.0%)
μ DPID	106	0.014 (5.7%)	0.017 (5.6%)	0.021 (3.1%)
	26.6	0.009 (9.7%)	0.0099 (9.3%)	0.01 (9.1%)
	13.7	0.0067 (10.7%)	0.0069 (13.3%)	0.0066 (11.3%)

^aThe snippets of the μ PID and μ DPID raw data are provided in Figures S15 and S16. The noise reported is for one standard deviation. The visual statistical representation of the noise presented in this table is depicted in Figure S17.

Additionally, the amplifier's input bias current can lead to a significant output signal offset. The INA121 amplifier has a much lower input bias current (~ 50 pA) than ~ 25 nA in INA122, which helps minimize this offset (~ 5 mV—see Table

S5) and eliminates the external offset tuning circuitry in the prior work.^{16,19}

μ DPID Chip Ambient-Coupled Noise Characterization. The μ DPID is a high-impedance current source (on the order of T Ω —see Table S3), and the amplifier used in the μ DPID readout circuit also has a very high input impedance (1000 G Ω —see Table S5). These points are highly sensitive to electrostatic and inductive coupling with nearby interference sources.²⁷ However, due to the high impedance nature of the μ DPID, electrostatic coupling is more dominant than the inductive coupling.²⁸ These electrostatic couplings for μ DPID with ambient sources can reach up to sub-nF.^{28,29} As a result, multiple sources may collectively raise the coupling capacitance to nearly sub- μ F levels.

The effect of these ambient electrostatic couplings in all four μ DPID chips was first examined without any shielding mechanism (such as a Faraday cage) and no heater installed, using three circuit configurations: standalone readout circuit (Figure S5A), μ DPID circuit (Figure S5B), and μ PID circuit (Figure S5C). The impact of the electrostatic coupling in these circuits is demonstrated in Figure 3, showing the dominant 60 Hz noise picked up by all four chip designs from the nearby devices. In all four designs, the noise in the μ DPID circuit was significantly lower than in the μ PID circuit due to the common-mode noise rejection feature built into the μ DPID (see Figure 3C and Table S6). However, the Design-1 μ DPID circuit exhibited substantially higher noise than the other three designs. We speculate that this design may be more susceptible to environmental changes, as it has a lower resistance between two electrodes compared to other designs (see Table S3) due

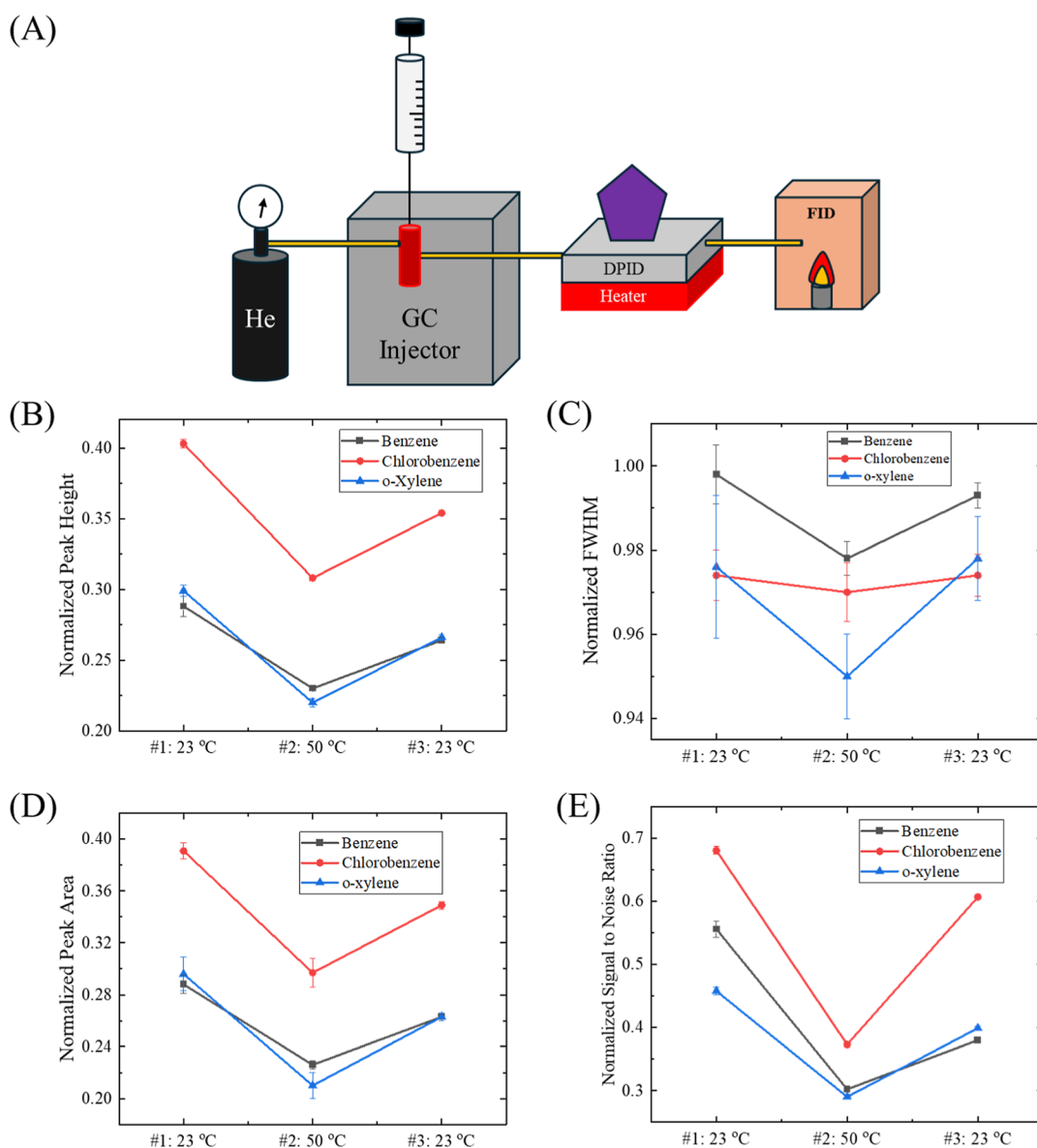


Figure 6. Characterization of μ DPID with standard gas models (such as benzene, chlorobenzene, and o-xylene) at 23 and 50 °C. (A) The experimental setup used for testing the μ DPID with standard gas. The FID detector on the benchtop GC connected in series with the μ DPID sensing channel served as a reference to compare the performance of the μ DPID at 23 °C (room temperature) and 50 °C. (B–E) Peak height, FWHM, peak area, and SNR of the gas peaks detected by the μ DPID normalized to the corresponding FID data. Error bars are obtained with \sim 10 measurements. The corresponding chromatogram is shown in Section S17, and Table S9 summarizes the parameters of the peaks detected by FID and μ DPID. Here, #1–23 °C indicates gas detection at $t = 0$ s when the μ DPID temperature was 23 °C. #2–50 °C signifies gas detection after heating the μ DPID module for \sim 15 min to reach \sim 50 °C, with 80% PWM applied to the heater. #3–23 °C represents gas detection after cooling the μ DPID back to 23 °C.

to the narrower gap (160 μ m) and longer channel (50 mm), which results in a higher leakage current.³⁰ On the other hand, in Designs 2, 3, and 4, the noise in the μ DPID circuit was similar to that in the standalone readout circuit. However, the standalone readout and μ DPID circuit still exhibited some residual common-mode 60 Hz noise as noted in Figure 3, which may be attributed to resistance mismatch between the sensing and reference channels in the μ DPID chip and/or in the resistive network at the input of IN121.

To further reduce the noise, the performance of the three circuits was evaluated by enclosing them inside a grounded solid Faraday cage (Figure S3A). From Figure S6A,C, it is evident that the noise of all circuits decreases significantly compared to their counterparts in Figure 3A,C. Additionally,

the FFT spectrum in Figure S6D shows that even with a Faraday cage, the μ PID circuit still exhibits electrostatic coupling at multiple frequencies. This electrostatic coupling at the μ PID circuit might be related to the efficiency of the Faraday cage, as studies have shown that, depending on the Faraday cage design, it may not fully attenuate coupling noises, due primarily to the conductivity of the Faraday cage metal, joints, gaps, probes, and fluidic openings in the cage.³¹ These Faraday cages may allow moisture to enter, increasing stray coupling. In contrast, the μ DPID dampened them (see Figure S6D) even with the above limitations, making it suitable for measuring currents as low as pA.

We further evaluated the long-term stability of the circuits (see Table S7). Although the noise in the μ PID circuits

fluctuates, the noise in the μ DPID circuits remains relatively stable over 2 days, highlighting the advantage of the μ DPID. An exception is the Design-1 μ DPID circuit, which shows a 93% increase in noise (while the Design-1 μ PID circuit experiences roughly a 520% increase). This may be due to the lower channel resistance of Design-1 compared to other designs (see Table S3), causing leakage currents in the μ DPID chip as observed in Figure 3 and Table S6. Additionally, comparing the noise levels of the other three designs (Design-2, Design-3, and Design-4) in Table S7, it appears that regardless of their symmetry, μ DPID circuits exhibit similar noise levels, likely because of their high channel resistance (see Table S3). Therefore, from now on, we will focus solely on Design-4 (shown in Figure 1E), enclosed in a Faraday cage (depicted in Figure S3A) for the subsequent sections, due to its simplicity and better fluidic isolation between the sensing and reference channels.

μ DPID Chip Heater and Temperature Related Noise Characterization. Moisture and volatile organic compounds (VOCs) condensation and accumulation on the VUV lamp window and PID electrodes are common issues in PID sensors, causing leakage currents and significantly reduced sensitivity. Adding an on-chip heater can help mitigate this issue. It also helps produce narrower peak widths for heavier VOCs when used with a GC system.¹⁸ However, adding an on-chip heater increases noise from higher operating temperatures and EMI caused by the heater's PWM. Among these, EMI noise is the most significant. Section S10 shows the effect of heater PWM-induced EMI on the μ PID (or μ DPID) signal using COMSOL. Additionally, methods to reduce this interference, such as positioning the heater farther from the detector, adding a grounded plane, using a high-frequency PWM, using an analog heater control, and other strategies, are examined in Section S11 and summarized in Table S8.

Our μ DPID included an on-chip heater integrated with a grounded plane (copper sheet in Figure 1F) and operated at a PWM frequency of 150 Hz. Performance tests comparing the μ DPID and the μ PID with the heater ON show that the μ PID detects a significant amount of 150 Hz EMI noise from the heater PWM, whereas μ DPID only detects a trace level of this noise at a 106 Hz signal bandwidth (see Figure 4A–C). Remarkably, the noise in the μ DPID with the heater ON is just ~ 0.017 mV, >10 times lower than the ~ 0.24 mV in the μ PID at the same bandwidth (see Figure 4D). The μ DPID and μ PID noise levels were also assessed at reduced bandwidths of 26.6 and 13.7 Hz (see Section S12). As expected, a lower noise was observed than at the 106 Hz bandwidth, as summarized in Figure 4D. Notably, the μ PID displayed greater noise variations at 26.6 Hz than the μ DPID, due to the 150 Hz heater PWM EMI being aliased at the 60 Hz ADC data sampling rate, as shown in Figure S12B. Additionally, Figures 4D and S12D indicate that the μ PID with heater ON can achieve a low noise level (~ 0.007 mV), similar to the μ DPID, only at the lower bandwidth of 13.7 Hz (see Figure 4D). Conversely, the μ DPID with the heater ON maintains a consistently low noise level (<0.02 mV) even at higher bandwidths of 106 and 26.6 Hz.

Furthermore, the temporal performance of the μ PID and μ DPID with the heater ON over 600 s, specifically during temperature ramping, was also examined at different bandwidths (see Section S12). Notably, at 106 Hz, the μ PID clearly exhibited an increase in noise of ~ 0.037 mV from $t = 0$ s at room temperature (23 °C) to 50 °C at $t = 600$ s, whereas

the μ DPID maintained a stable noise level over the entire 600 s.

Section S13 evaluates the impact of PWM duty on the μ PID and μ DPID noise. It was observed that the noise levels of both μ DPID and μ PID grow as the duty cycle increases, especially at the 106 Hz bandwidth. Nevertheless, the μ DPID noise increased by only ~ 0.01 mV, whereas the μ PID noise rose by ~ 0.25 mV when the PWM duty cycle increased from 10% to 60% at the 106 Hz bandwidth. Moreover, no significant noise increase was detected in the μ DPID with duty cycle changes for bandwidths of 26.6 and 13.7 Hz, whereas the μ PID showed no increase only at the lowest bandwidth of 13.7 Hz.

μ DPID Device Characterization. All μ DPID characterizations performed thus far did not involve a VUV lamp or plasma generation. The μ DPID shown in Figure 1F,G employs a commercial Mocon circuit (~ 960 V peak-to-peak sinusoidal output at ~ 108 kHz—see Figure S14) to power the VUV lamp. Plasma generation usually produces two kinds of noise: shot (white) noise from plasma photons and EMI from the plasma excitation circuit.²² In practice, shot noise is minimal compared to EMI noise, since the electrodes for high-voltage/frequency plasma generation are close to the μ DPID. Consequently, shielding this EMI noise with a Faraday cage described earlier is impractical. Usually, this high-frequency noise appears as low-frequency harmonics in the μ PID/ μ DPID signal because of signal aliasing caused by the low ADC data sampling rate (for instance, 400 Hz sampling rate for the 106 Hz bandwidth—see Table S4).

Figure 5A,B show the noise of the μ PID and μ DPID increased by about 0.004 mV and 0.003 mV, respectively, when the VUV lamp was ON (but the heater was OFF). The FFT spectra in Figure 5C,D reveal that the noise increase occurred uniformly across all frequencies, indicating a rise in broadband (white) noise, which may be caused by the addition of white noise into the μ DPID's sensing channel (and μ PID as well) from the VUV photons. However, despite broadband noise, comparison between Figure 5C,D shows that no additional prominent frequency noise component emerges when the VUV lamp is ON. This probably results from effective high-frequency filtering by the second-order 106 Hz low-pass filter and low EMI generated by the piezoelectric transformer used in the Mocon plasma generation circuit,³² compared to a magnetic transformer³³ used in the prior work.¹⁶ Note that the minimal noise increase (~ 0.003 mV) also justifies our VUV lamp placement fully on the μ DPID's sensing channel (as depicted in Figure 1A) for maximal usage of VUV photons, thereby maintaining the gas detection sensitivity reported in our previous work.^{16,18} The μ PID and μ DPID noise was further evaluated at lower bandwidths of 26.6 and 13.7 Hz when the heater was OFF. Figure S15 shows that both the μ PID and μ DPID noise levels decrease as the signal bandwidth decreases, as expected. The combined effect of plasma ON and heater PWM ON for both the μ PID and μ DPID was investigated in Figure S16. All the noise values for all conditions, lamp OFF and heater OFF, lamp ON but heater OFF, and both lamp and heater ON, are summarized in Figure S17 and Table 1.

In Section S16, the temporal performance of both μ PID and μ DPID was also assessed when the heater was OFF and ON (and the VUV lamp remained ON) at a 106 Hz bandwidth. Figures S18C and S19C show that the μ DPID's noise remained low and stable over time compared to the μ PID. However, both μ PID and μ DPID exhibited a baseline drift of

~4 mV with temperature ramping (Figure S19B), compared to the constant baseline observed with the heater OFF (Figure S18B). However, the baseline for both μ PID and μ DPID stabilized once the target temperature (~50 °C) was reached.

Characterization of μ DPID as GC Detector at 23 and 50 °C. The performance of the μ DPID was further evaluated using benzene, chlorobenzene, and *o*-xylene as gas models, with the FID connected in series with the μ DPID sensing channel serving as the reference. The detailed experimental setup is outlined in the section Experimental Setup for μ DPID as Gas Detector and is visually represented in Figure 6A. Experiments were conducted at two μ DPID temperatures, 23 °C (room temperature) and 50 °C. The corresponding raw data is provided in Section S17.

Analysis of Figure 6B,D reveals that both the normalized peak height and peak area for all gases decrease at 50 °C compared to 23 °C. This decline is likely attributable to the faster transit time of the gases through the channel at elevated temperatures, as evidenced by a reduction in the full width at half-maximum (FWHM) for these gases at 50 °C. Table S9 further indicates that the fwhm of the gases correlates positively with their boiling points: *o*-xylene exhibits the highest FWHM of ~2.3 s, whereas benzene shows the lowest of ~0.73 s. These values also decrease at 50 °C, as shown in Figure 6C. Notably, by increasing the flow rate to 3 mL/min, the FWHM of benzene decreased by 45% in the μ DPID. (see Table S9 and Figures S20 and S23).

Additionally, from Figure 6E, the signal-to-noise ratio (SNR) decreases at #2–50 °C compared to #1–23 °C and #3–23 °C for all three gases. This decline may result from both the lower peak height and increased baseline noise when the heater is ON in the μ DPID, as discussed earlier in Table 1. However, based on the SNR values at #1–23 °C and #3–23 °C, it appears that thermal cycling of the μ DPID has minimal impact on the μ DPID performance.

CONCLUSIONS

In this study, a μ DPID was developed to enhance the operational bandwidth while simultaneously minimizing noise. A comprehensive evaluation of the μ DPID's performance was conducted in comparison to the μ PID configuration under various noise conditions, demonstrating that the μ DPID can operate reliably at a bandwidth of 106 Hz with a linear dynamic range of $\sim 2 \times 10^5$ (from 3.85 V to 0.021 mV or 38.5 nA to 0.21 pA) at a temperature ranging from 23 to 50 °C. These capabilities underscore the μ DPID's significant potential in advancing portable ultrafast μ GC and comprehensive two-dimensional μ GC for field-deployable applications.

The overall noise level of the μ DPID device is observed to be comparable to the intrinsic noise of the INA121-based readout circuit, which is primarily dominated by the thermal noise inherent to the 100 M Ω gain resistor. To further enhance the SNR, a larger gain resistor can be used. For instance, a 2 G Ω gain resistor, analogous to that employed in a transimpedance amplifier,³⁴ would augment the SNR by a factor of 4.5. Furthermore, a new electrometer amplifier sensitive to femtoampere can also be explored.³⁴ Finally, increasing the voltage supply in INA121 beyond the current level of 4.75 V can expand the maximum output voltage and hence the dynamic range.

ASSOCIATED CONTENT

Supporting Information

The Supporting Information is available free of charge at <https://pubs.acs.org/doi/10.1021/acs.analchem.5c05021>.

Micro-Gas detectors, noise sources for μ PID, design and fabrication of μ DPID Chips, μ DPID device architecture, and characterization, strategies to reduce heater PWM-related EMI, characterization of μ DPID as GC detector (PDF)

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Notes

The authors declare the following competing financial interest(s): X.F. is an inventor of the microfluidic photoionization detector technology that is related to the device described in this article. This technology is licensed to Nanova Environmental, Inc., ChromX Health Co., Ltd, and RUA Diagnostics, in which X.F. has financial interest.

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